

# United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/826,259	04/19/2004	Syotaro Ono	251907US-2S DIV	9423
22850	7590 10/14/2005		EXAMINER	
OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C.			PHAM, LONG	
1940 DUKE S ALEXANDR	STREET IA, VA 22314		ART UNIT	PAPER NUMBER
	, ··· ·		2814	<u> </u>
			DATE MAILED: 10/14/200	5

Please find below and/or attached an Office communication concerning this application or proceeding.

				$H_{i}$		
		Application No.	Applicant(s)			
Office Action Summary		10/826,259	ONO ET AL.			
		Examiner	Art Unit			
		Long Pham	2814			
Period fo	The MAILING DATE of this communication apor Reply	opears on the cover sheet w	vith the correspondence address			
WHIC - Exte after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REP CHEVER IS LONGER, FROM THE MAILING I nsions of time may be available under the provisions of 37 CFR 1 SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period to reply within the set or extended period for reply will, by staturely received by the Office later than three months after the mailed patent term adjustment. See 37 CFR 1.704(b).	DATE OF THIS COMMUN  1.136(a). In no event, however, may a d will apply and will expire SIX (6) MO ate, cause the application to become	ICATION. I reply be timely filed INTHS from the mailing date of this communication. ABANDONED (35 U.S.C. § 133).			
Status						
1)	Responsive to communication(s) filed on	·				
-		is action is non-final.		٠		
3)[	Since this application is in condition for allow	ance except for formal ma	tters, prosecution as to the merits is			
	closed in accordance with the practice under	Ex parte Quayle, 1935 C.	D. 11, 453 O.G. 213.			
Disposit	ion of Claims					
4)⊠	Claim(s) 31-35 is/are pending in the applicati	ion.				
•	4a) Of the above claim(s) is/are withdrawn from consideration.					
5)⊠	Claim(s) 34 and 35 is/are allowed.	0				
6)⊠	Claim(s) 31 is/are rejected.					
7)🛛	Claim(s) 32 and 33 is/are objected to.					
8)[	Claim(s) are subject to restriction and	or election requirement.				
Applicat	ion Papers		•			
9)[	The specification is objected to by the Examir	ner.				
10)	The drawing(s) filed on is/are: a) ac	ccepted or b)  objected to	by the Examiner.			
	Applicant may not request that any objection to th	e drawing(s) be held in abey	ance. See 37 CFR 1.85(a).			
	Replacement drawing sheet(s) including the corre	ection is required if the drawin	g(s) is objected to. See 37 CFR 1.121(d)	•		
11)	The oath or declaration is objected to by the B	Examiner. Note the attach	ed Office Action or form PTO-152.			
Priority (	under 35 U.S.C. § 119					
	Acknowledgment is made of a claim for foreig ☐ All b)☐ Some * c)☐ None of:		§ 119(a)-(d) or (f).			
	1. Certified copies of the priority document		Angliantian Na			
	<ul><li>2. Certified copies of the priority document</li><li>3. Copies of the certified copies of the priority</li></ul>		<del></del>			
	application from the International Bure	•	in received in this National Stage			
* 5	See the attached detailed Office action for a list		at received.			
		·				
Attachmer	nt(s)			٠		
	ce of References Cited (PTO-892)		Summary (PTO-413)			
3) Infor	ce of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/0 er No(s)/Mail Date		o(s)/Mail Date Informal Patent Application (PTO-152) 			

Application/Control Number: 10/826,259 Page 2

Art Unit: 2814

#### **DETAILED ACTION**

# Rejections and/or objections necessitated by the amendments \*Claim Rejections - 35 USC § 103\*\*

- 1. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.
- 2. Claim 31 is rejected under 35 U.S.C. 103(a) as being unpatentable over Baliga (US patent 5,637,898) in combination with Hshieh et al. (US patent 6,518,127).

With respect to claim 31, Baliga teaches a method of manufacturing a power MOSFET, comprising (see figs. 2A-2K and 3 and associated text): epitaxially growing a drift layer 112 of a first conductivity type (n) on a first conductivity type semiconductor substrate 114 used as a drain layer, said

drift layer being doped with impurities having a concentration distribution increasing up to or toward said substrate (see abstract);

forming a base layer 116 of a second conductivity type (p) on said drift layer;

forming a source region 118 of the first conductivity type (n) on said base layer;

forming a trench penetrating said source region and said base layer to reach at said drift layer; and

forming trenched gate structure including a gate insulating film 124 and a gate electrode 126, said gate insulating film having a thin portion facing said base layer and a thick portion facing said drift layer.

Baliga fails to teach that the base layer is formed by epitaxial growth.

However, the formation of semiconductor layers by epitixial growth is well-known in the art.

Art Unit: 2814

Further with respect to claim 31, Baliga fails to teach that a bottom portion of the trenched gate structure reaches into the drain layer.

Hshieh et al. teach that a bottom portion of a trenched gate structure 118, 125 reaches into a drain layer 111 to reduce unwanted resistance. See fig. 3 and associated text of Detailed of Description of Hshieh et al.

It would have been obvious to one of <u>ordinary skill</u> in the art of making semiconductor devices to incorporate the teaching of Hshieh et al. into the method of Baliga to achieve the above benefit.

## Allowable Subject Matter

- 1. Claims 32 and 33 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.
- 2. Claims 34 and 35 are allowed.

### Conclusion

3. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will

Application/Control Number: 10/826,259 Page 4

Art Unit: 2814

the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Long Pham whose telephone number is 571-272-1714. The examiner can normally be reached on M-F, 7:30AM-3:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Wael Fahmy can be reached on 571-272-1705. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Long / Pham

Primary Examiner

Art Unit 2814